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PATENT APPLICATION
ATTORNEY DOCKET NO. LMRX-P028/P1187

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: STEGER

Examiner: UNKNOWN

Application No. 10/720,839

Group No. 2858

Filed: 11/24/2003

Confirmation No. 3615

Title: METHODS AND APPARATUS FOR
IN SITU SUBSTRATE TEMPERATURE
MONITORING

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the US Postal Service as First Class Mail in a postage-paid envelope addressed to the Assistant Commissioner for Patents, Washington, DC 20231 on February 10, 2005.

Signed: /Hanh H. Bui/
Hanh H. Bui

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to the patentability of the above-identified patent application. Applicants submit the list of these references in compliance with their duty of disclosure pursuant to 37 CFR §§ 1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

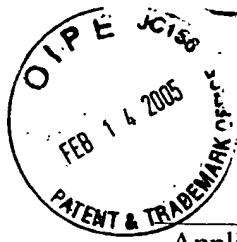
This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is believed to be filed after the mailing date of a first Office Action on the merits. A credit card payment of \$180.00 is enclosed. However, if it is determined that additional fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 50-2284 (Order No. LMRX-P028).

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Respectfully submitted,
By: /Joseph Nguyen/
Joseph Nguyen
Reg. No. 37,899



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US PATENT DOCUMENTS

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	36	U.S. Patent Application No.: 10/608,091 File Date: June 30, 2003 Attorney Docket Number: 015290-682 Inventor: Steger	

Examiner Signature		Date Considered	
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